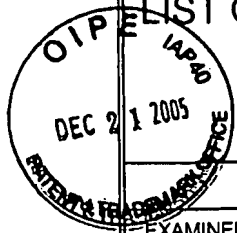


12/21/05



LIST OF ART CITED BY APPLICANT
(PTO-1449)

ATTY. DOCKET NO. ASU-0001	APPLN. SERIAL NO. 10/626,880
APPLICANT(S) Susan D. ALLEN and Sergey I. KUDRYASHOV	
FILING DATE 7/25/2003	GROUP

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	5,023,424	6/11/91	Vaught	219	121.6	1/22/90
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	*APPLN. NO.	*FILING DATE	*INVENTOR	CLASS	SUBCLASS	
			<i>[Signature]</i>			

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
			<i>[Signature]</i>				

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(PTO-1449)

OTHER ART (Including Author, Title, Date, Pertinent Pages, Publisher, Place of Publication, Etc.)

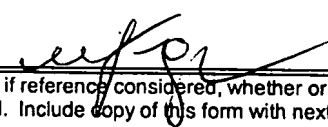
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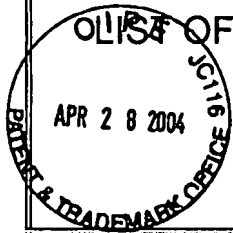
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SHEET 3 OF 3

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EXAMINER	DATE CONSIDERED
	04/29/07

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

04/28/2004



LIST OF PRIOR ART CITED BY APPLICANT
(PTO-1449)

ATTY. DOCKET NO.
ASU-0001

APPLN. SERIAL NO.
10/626,880

APPLICANT(S)
Susan D. ALLEN and Sergey I. KUDRYASHOV

CUSTOMER NO. 34610

FILING DATE
July 25, 2003

GROUP

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FOREIGN PATENT DOCUMENTS

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DATE CONSIDERED

04/27/07